

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in this application:

**LISTING OF CLAIMS:**

1. (Currently Amended) A micromechanical component, comprising:

a supporting body;

at least one at least partially unsupported membrane connected to the supporting body;

at least one stabilizing element provided in an unsupported area on some areas of a surface of the at least one membrane,

wherein the at least one membrane extends continuous over an entire recess etched in the supporting body, and a portion of the at least one stabilizing element contacts only the membrane for a part less than a whole length depth of the recess of the membrane and a portion of the at least one stabilizing element is positioned between the supporting body and the at least one membrane, and

wherein at least a part of the stabilizing element is exposed to the recess etched in the supporting body wherein the at least one stabilizing element includes at least a ring-shaped skirt arranged around one of recesses and etching holes in the at least one membrane, and

wherein the micromechanical component is configured as a thermal membrane sensor and the at least one stabilizing element is configured to counteract a deformation of the at least one membrane.

Claims 2 and 3. (Canceled).

4. (Original) The micromechanical component according to claim 3, wherein:  
the deformation includes one of a warping, a propagation of cracks, and a propagation of stresses in the at least one membrane.

5. (Previously Presented) The micromechanical component according to claim 1, wherein:  
the at least one stabilizing element includes one of:  
a web,

a plurality of webs,  
parallel webs,  
an arrangement of webs configured in a mesh,  
an arrangement of webs configured in a grid,  
a web designed as a ring,  
a plurality of webs designed in concentric rings, and  
a stabilizing area designed in the shape of one of a tongue and a rod.

**6. (Original) The micromechanical component according to claim 1, wherein:**  
**the at least one stabilizing element includes at least one of:**

**a ring-shaped skirt arranged around one of recesses and  
etching holes in the at least one membrane, and  
a stabilizing surface in corner areas of the at least one  
membrane.**

**7. (Original) The micromechanical component according to claim 1, wherein:**  
**the at least one stabilizing element is arranged on one side of the at least one  
membrane facing the supporting body.**

**8. (Original) The micromechanical component according to claim 1, wherein:**  
**the at least one stabilizing element is in direct contact with the at least one  
membrane and is bonded thereto in at least some areas in the unsupported area.**

**Claim 9. (Canceled).**

**10. (Original) The micromechanical component according to claim 1, wherein:**  
**the supporting body includes a silicon body.**

**11. (Original) The micromechanical component according to claim 1, wherein:**  
**the at least one membrane includes a silicon compound and has a thickness  
of 10 nm to 10  $\mu$ m.**

**12. (Original) The micromechanical component according to claim 11,  
wherein:**

the silicon compound includes one of a silicon nitride layer, a silicon carbide layer, and a silicon dioxide layer.

13. (Previously Presented) The micromechanical component according to claim 1, further comprising:

a circuit structure positioned on the at least one membrane.

14. (Original) The micromechanical component according to claim 13, wherein:

the circuit structure includes at least one of at least one thermocouple and a sensitive component of a sensor element.

15. (Original) The micromechanical component according to claim 1, wherein: a thickness of the at least one stabilizing element is between 10 nm and 5  $\mu$ m.

Claims 16 to 24. (Canceled).